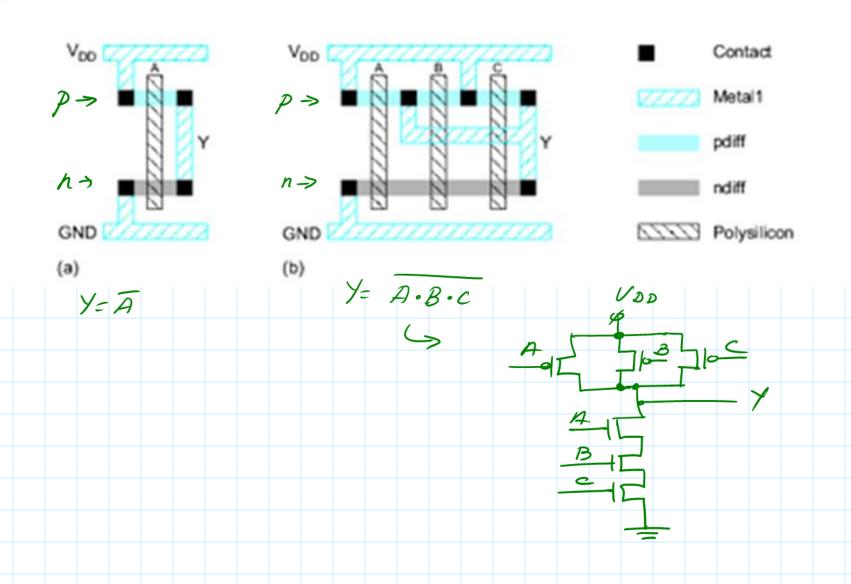
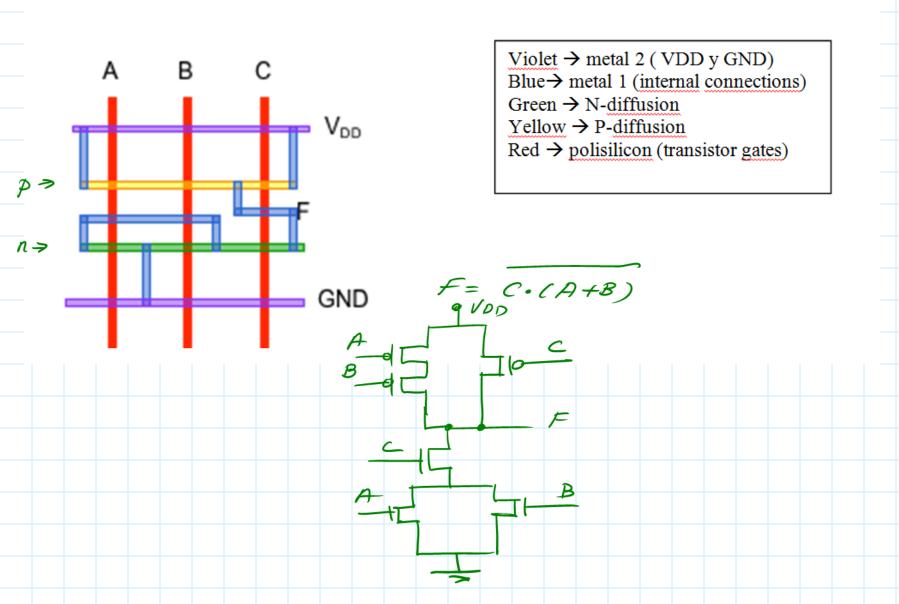
5.1. Indicate the logic function that implements the standard cell with the layouts of the figure:



5.2. From layout diagram of the figure, indicate the logic function that implements the standard cell.



of the masks

- 5.3. Indicate whether they are true (V) or false (F) the following statements on the photolithographic manufacturing process of CMOS IC:
- a) Usually, a circular silicon wafers are used as substrate ✓
- b) Each wafer contains a single chip *F*
- c) They are deposited layers (layers) of different materials in a bottom-up way /
- d) The typical order in the deposition of layers is: 1) n + and p + areas of S and D, 2) metal interconnections, 3) thin insulating layer of gate, 4) polysilicon of the gate
- e) UV light is used to project the masks on the wafer 🗸
- f) Once you have the chips on the wafer substrate, they are cut, tested and encapsulated  $\sqrt{\phantom{a}}$
- 5.4. If we compare the standard cell based design with full-custom design, we can say that:
- A) The semi-custom design based on cells optimizes the speed and silicon occupied  $\times$ area.
- B) The full-custom design is getting more automated, minimizing the design time C) The full-custom design is done with layout editors, making the geometric description
- D) In the cell design, the smallest units of design are the transistors, which are stored in
- libraries

3.4. The figure shows 8 open-drain outputs connected to a bus. Only one gate is enabled at a time, remaining the other with a high level at the output. Indicate the maximum and minimum pull-up resistor R, according to the following specifications of the logic gates:

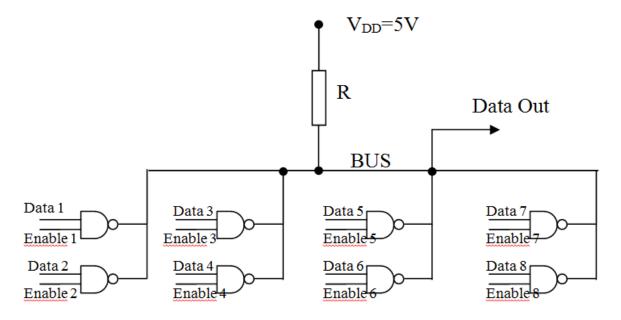
#### (74HC gates specifications):

 $I_{OLmax} = 4mA$ ,

 $V_{OLmax} = 0.33V$ 

 $V_{OHmin} = 3.84V$ 

 $I_{OHmax} = 5\mu A$  (leakage current at the output when High)



- A)  $0.5K \le R \le 4K7$
- B)  $0.5K \le R \le 10K$
- $\stackrel{\frown}{C}$  1.5K  $\leq$  R  $\leq$  3K3
- (D)  $1.17K \le R \le 29K$

